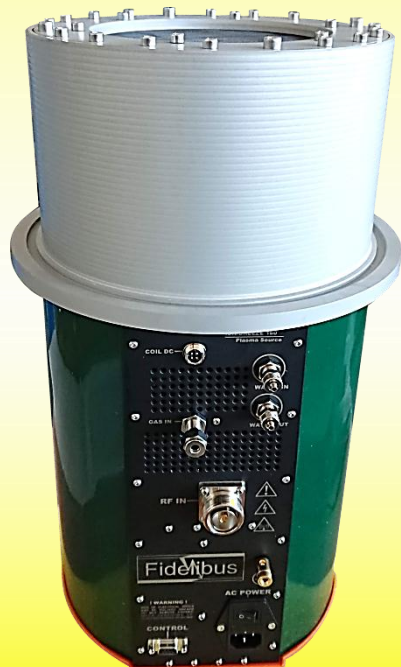


RF Self-Neutralized Ion Sources

«BREEZE» - Series

Fidelibus

Industrial RF Plasma Systems



In a wide application range

Plasma Cleaning

Surface activation

PVD Assisting

PECVD

- Built-in impedance matching network (M'Box).
- Not required neutralizer.
- Easy control by communication port or wireless interface.
- Flexible Ion energy control.
- High density of ion current.
- Ion flux without contaminations.
- Long lifetime, easy maintenance.

Parameter	Value	Parameter	Value
Working frequency	13.56 MHz	Energy control	Remote / Manual
Matching impedance control	Remote / Manual	RF input	7/16
Working power	300-10000 W	Input Impedance	50 Ohm
Ion Energy	30-350 eV	Power connection	110-220 V; 50 / 60 Hz
Current density	Up to 5 mA / cm ²	Magnetic field	DC Coil
Working pressure	0,02-0,5 Pa	Cooling	Water/Fan
Type of gas	Any gases	Grid	Tungsten